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TECHNOLOGY CENTER 2800

APPLICANT(S): Tony P. Chiang and Karl F. Leeser

SERIAL NO.: 09/994,279

FILED: November 26, 2001

TITLE: Method for Integrated In-Situ Cleaning and Subsequent Atomic Layer Deposition Within A Single Processing Chamber

EXAMINER: Unknown

GROUP ART UNIT: 2812

ATTY.DKT.NO.: PA1688US

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INFORMATION DISCLOSURE STATEMENT
Under 37 C.F.R. §§ 1.56, and 1.97-1.98

SIR:

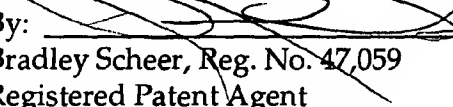
Pursuant to the provisions of 37 C.F.R. §§ 1.56 and 1.97-98 of the Rules of Practice in Patent Cases, enclosed herewith is form PTO-SB-08 listing several references, copies of which are enclosed. The Examiner is requested to make these references of official record in the application. The references cited may be material to examination of the application and are submitted in compliance with Applicants' duty of disclosure as defined by 37 C.F.R. § 1.56.

No representation is made or intended as to the completeness of this list, nor is the inclusion of any reference on this list an admission that it is prior art or pertinent to this application.

Respectfully submitted,

Tony P. Chiang and Karl F. Leeser

Dated: MARCH 14, 2002

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